



ABSTRACT

Disclosed herein are an anisotropically conductive connector, by which positioning, and holding and fixing to a wafer to be inspected can be conducted with ease even
5 when the wafer has a large area, and the pitch of electrodes to be inspected is small, and moreover good conductivity can be achieved as to all conductive parts, and insulating property between adjacent conductive parts can be achieved, a production process thereof, and a probe
10 member.

The anisotropically conductive connector comprises a frame plate having a plurality of anisotropically conductive film-arranging holes formed corresponding to regions of electrodes to be inspected of a wafer, and a
15 plurality of elastic anisotropically conductive films arranged in the respective anisotropically conductive film-arranging holes and supported by the inner peripheral edge thereof. Each of the elastic anisotropically conductive films is composed of a functional part composed of a
20 plurality of conductive parts arranged corresponding to the electrodes to be inspected, containing conductive particles exhibiting magnetism at a high density and extending in the thickness-wise direction of the film and insulating parts mutually insulating these conductive parts, and a supported
25 part integrally formed at a peripheral edge of the functional part and fixed to the inner periphery about the anisotropically conductive film-arranging hole. The



- supported part contains the conductive particles exhibiting
- magnetism.